

## WAFER-TO-WAFER ADVANCED PROCESS CONTROL FOR CMP APPLICATIONS

### Who should attend?

This course is designed for those individuals in the semiconductor industry who require the knowledge to utilize the Advanced Process Control methodology.

### Course Benefits

Provides an overview of the methodology and technology behind Advanced Process Control (APC) for Chemical Mechanical Planarization (CMP) applications.

### Course Objective Summary

- Describe the purpose of Advanced Process Control (APC).
- Describe the hardware platforms that utilize APC.
- Describe the process applications that use APC.

### Registration Information

**Prerequisites:** None  
**Course Length:** 1.5 Hours  
**Course Type:** Web-based Training  
**Course Number:** TRNWEB-153

To enroll or for more information on our products and services, please call our registrar at one of the numbers below or go to [www.appliedtraining.com](http://www.appliedtraining.com).

- 1-800-468-8888, option 4 (United States)
- 1-512-272-0027 (International)

### Computer System Requirements:

Attending this course requires a Windows 98, NT, 2000 or XP computer using Internet Explorer 5.5 or higher. 128MB RAM or higher and high-speed Internet access is also highly recommended.